Sheet U.S. Dept. of Commerce Attorney Docket No.: Serial No.: 09/960,479 Patent and Trademark Office Applicant: Tokuda, Mitsuo, et al. **INFORMATION DISCLOSURE** CITATION (Use several sheets if necessary) Filing Date: September 24, 2001 Group: U.S. PATENT DOCUMENTS FILING DATE Initial* REF DOCUMENT NUMBER DATE IF APPROPRIATE CLASS NAME CLASS 6 10/09/84 Reid, et al. AA 6 8 250 310 2 5 2 AB 5 0 5 12/14/93 Ohnishi, et al. 250 307 **FOREIGN PATENT DOCUMENTS** SUB-TRANSLATION **DOCUMENT NUMBER** DATE COUNTRY CLASS **CLASS** YES NO JH 07/21/98 **EU** Application AC 0 2 **G01N** 1/28 X AD ΑE OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.) Ohnishi, T., et al., "A new focused-ion-beam microsampling technique for TEM observation of site-specific areas." ISTFA '99. Proceedings of the 25th International Symposium for Testing AF and Failure Analysis. ASM Int. 1999, pp. 449-53 (14-18 Nov. 1999). Materials Parks, OH, USA Pawley, James B., "A Dual Needle Piezoelectric Micromanipulator for the Scanning Electron Microscope." The Review of Scientific Instruments, Vol. 43, No. 4, April 1972. JIL AG AΗ DATE CONSIDERED **EXAMINER**

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